Docket No.: 740756-2688

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)
Etsuko ASANO et al.	)
Application No.: 10/735,627	) Examiner: Unknown
Filed: December 16, 2003	) Group Art Unit:
For: An Evaluation Method using a TEG, A Method of manufacturing a Semiconductor Device Having the TEG, An Element Substrate and A Pannel Having the TEG, A Program for Controlling Dosage and A Computer-Readable Recording Medium recording the Program	) Not Yet Assigned))))

VERIFICATION OF TRANSLATION

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Sir:

I, Mika Tatsumi, C/O Semiconductor Energy Laboratory Co., Ltd. 398, Hase, Atsugi-shi, Kanagawa-ken 243-0036 Japan, a translator, herewith declare:

that I am well acquainted with both the Japanese and English Languages;

that I am the translator of the attached translation of the US Patent Application No. 10/735,627 filed on December 16, 2003; and

that to the best of my knowledge and belief the followings is a true and correct translation of the US Patent Application No. 10/735,627 filed on December 16, 2003.

I further declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issuing thereon.

Date: this 23th day of July, 2004

Mika Tatsumi

Name: Mika Tatsumi